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Applicants: Bipin S. Parekh, Jeffrey J. Spiegelman,
Robert S. Zeller and Russell J. Holmes

Title: LITHOGRAPHIC PROJECTION APPARATUS,
PURGE GAS SUPPLY SYSTEM AND GAS
PURGING METHOD

Attorney's Docket No.: 3194.1033-013

Date: 20 January 2006

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PRELIMINARY AMENDMENT

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please amend the application as follows: